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(54) Title: COMMON RESOURCE SHARING AND MANAGEMENT FOR SUBSTRATE PROCESSING SYSTEMS

(57) Abstract: A method including processing substrates in two stations on sep-
arate processing lines. In the first station of the first processing line, the method
may include: loading a first substrate, and delivering a resource for a first con-
figurable period, during which the resource is locked out from the first station
of the second processing line. In the first station of the second processing line,
the method may include: loading a second substrate, and delivering a resource
for a second configurable period, during which the resource is locked out from
the first station of the first processing line.

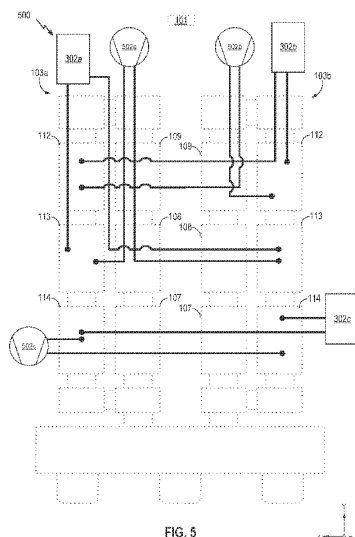


FIG. 5

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